# Gallium Arsenide

**Epitaxy Ready Polished Wafers** 



Wafer Technology offers single crystal Gallium Arsenide grown at low pressure from high purity polycrystalline Gallium Arsenide in a vertical temperature gradient (VGF-Vertical Gradient Freeze).

## MECHANICAL SPECIFICATIONS

Gallium Arsenide can be supplied in as-cut, etched or polished wafer forms. All slices are individually laser scribed with ingot and slice identity to ensure perfect traceability.

## **ORIENTATION SPECIFICATIONS**

Surface orientations are offered to an accuracy of  $\pm$ 0.05 degrees using a triple axis X-Ray diffractometer system. Substrates can also be supplied with very precise misorientations in any direction from the growth plane. Higher index substrates of the type (n,1,1) where n = 1,2,3,4,5,6 etc and orientations such as (110) are also available. We also offer wafers with cut and/or cleaved flats.

#### SURFACE SPECIFICATIONS

All wafers are offered with high quality epitaxyready finishing. Surfaces are characterised by in-house, advanced optical metrology techniques which include Surfscan haze and particle monitoring, spectroscopic ellipsometry and grazingincidence interferometry.

## **PACKAGING**

## **Polished Wafers**

Coin-style wafer shipper, individually sealed in two outer bags in inert atmosphere. Cassette shipments are available on request.

## **As-cut Wafers**

Cassette shipment. (Glassine bag available on request).

### 'Process Trial' wafers

Coin-style wafer shipper, individually sealed in one outer bag.

If you do not see the specification you require, please call for details on +44 (0)1908 210444 or email sales@wafertech.co.uk

Wafer Specifications						
Diameter Slices	<b>2</b> "	3"				
Orientation	(100) ± 0.1°	(100) ± 0.1°				
Diameter (mm)	50.5 ± 0.5	76.2 ± 0.4				
Flat Option	EJ	EJ				
Flat Tolerance	± 0.5°	± 0.5°				
Major Flat Length (mm)	16 ± 2	22 ± 2				
Minor Flat Length (mm)	8 ± 1	11 ± 1				
Thickness (µm)	350 ± 25 or 500 ± 25	625 ± 25				

Electrical and Doping Specifications							
Dopant	Туре	Resistivity Ω cm	Carrier Concentration cm <sup>-3</sup>	Mobility cm <sup>2</sup> V <sup>-1</sup> s <sup>-1</sup>	E.P.D. cm <sup>-2</sup>		
Undoped	Semi- Insulating	≥10 <sup>7</sup>	Not specified	≥5000	2" ≤2000 3" ≤5000		
Zinc	p-type	Not specified	5 x 10 <sup>18</sup> - 5 x 10 <sup>19</sup>	Not specified	2"≤3000 3"≤5000		
Mid Silicon	n-type	Not specified	(1-10) x 10 <sup>17</sup>	≥2000	2"≤1500		
High Silicon	n-type	Not specified	(1-5) x 10 <sup>18</sup>	Not specified	2"&3" Grade 1 ≤100 Grade 2 ≤500		

Tighter electrical ranges are available on request.

Flatness Specifications							
Wafei	Form	<b>2</b> "	3"				
	TTV (µm)	<10	<10				
Polish/Etched	Bow (µm)	<10	<10				
	Warp (µm)	<10	<10				
	TTV (µm)	<3	<5				
Polish/Polish	Bow (µm)	<3	<5				
	Warp (µm)	<10	<10				







